5

10

15

## ALIGNMENT APPARATUS, ALIGNMENT METHOD, EXPOSURE APPARATUS AND EXPOSURE METHOD

## ABSTRACT OF THE DISCLOSURE

An alignment apparatus, comprising a position detection optical system which detects a position of a mark formed on a street line of a substrate and a focus detection system which detects deviation between an irradiated region and a focused surface of the position detection optical system by irradiating a detection light on a region of said street line and a different region from a region of said mark at a time and detecting a reflected light of the detection light.